

**Amendments to the Claims:**

1. (Canceled)
2. (Previously Presented) A microelectromechanical (MEMS) structure on a substrate, comprising:
  - an actuator body connected with a suspension system; and
  - the suspension system connected with the substrate, the suspension system comprising:
    - a set of one or more flexures, each flexure connecting the actuator body with the substrate; and
    - a set of one or more torsional elements, wherein each torsional element connects a corresponding flexure with the actuator body and provides strain relief between the corresponding flexure and the actuator body.
3. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element relieves angular strain caused by a difference between the angle of the corresponding flexure and the angle of the actuator body.
4. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has an angle of twist per unit moment ( $\theta/\text{Nm}$ ) of 7.00E+06 or greater.
5. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has a length dimension that extends from the corresponding flexure to the actuator body, the length dimension having a value equal to or greater than 5 $\mu\text{m}$ .
6. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has a width dimension that extends perpendicular to the length dimension and substantially parallel to the substrate, the width dimension having a value equal to or greater than 2 $\mu\text{m}$  and less than 10 $\mu\text{m}$ .
7. (Previously Presented) The MEMS structure of claim 2, wherein a torsional element comprises a torsional attachment or a torsional spring.

8. (Currently Amended) The MEMS structure of claim [[2]] 7, wherein a torsional element is shaped in a serpentine form.

9. (Previously Presented) The MEMS structure of claim 2, wherein:

the suspension system further comprises a set of one or more anchor points, wherein each anchor point connects a corresponding flexure to the substrate and has an angle of twist per unit moment value substantially equal to a first value; and

each torsional element has an angle of twist per unit moment value substantially equal to a second value, wherein the second value is greater than the first value.

10. (Previously Presented) The MEMS structure of claim 2, wherein the actuator body is a platform, actuator segment, or mirror segment.